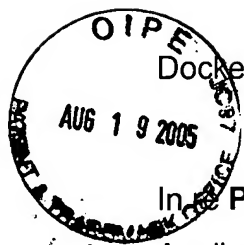


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Docket No. 03-IMP-031

IFW
EATNP159US



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In ~~the~~ **PATENT** application of:

Applicants: Halling et al.
Application No.: 10/825,527
For: BEAM ANGLE CONTROL IN A BATCH ION IMPLANTATION
SYSTEM
Filing Date: April 15, 2004
Examiner: Jack I. Berman
Art Unit: 2881

REPLY TO OFFICE ACTION DATED JULY 26, 2005

Mail Stop Amendment
Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following amendments and remarks.